



Patent No.: 49657-961

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

Filed: January 26, 2001

Group Art Unit: 2882

Examiner: C. Kao

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE

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INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each reference was first cited in a corresponding foreign application search report or office action and its relevance discussed therein. A copy of the foreign search report or office

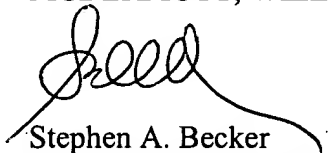
action, together with an English language version thereof, is attached for the Examiner's information.

Please note that the Japanese Patent Laying-Open No. 11-14800 was previously submitted on January 26, 2001. Therefore, only the first page is being submitted herewith. Also attached are the corresponding U.S. Patent No. 6,251,567 of the Japanese Patent Laying-Open No. 11-160871 and Korean Patent Laying-Open No. 1999-29914.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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